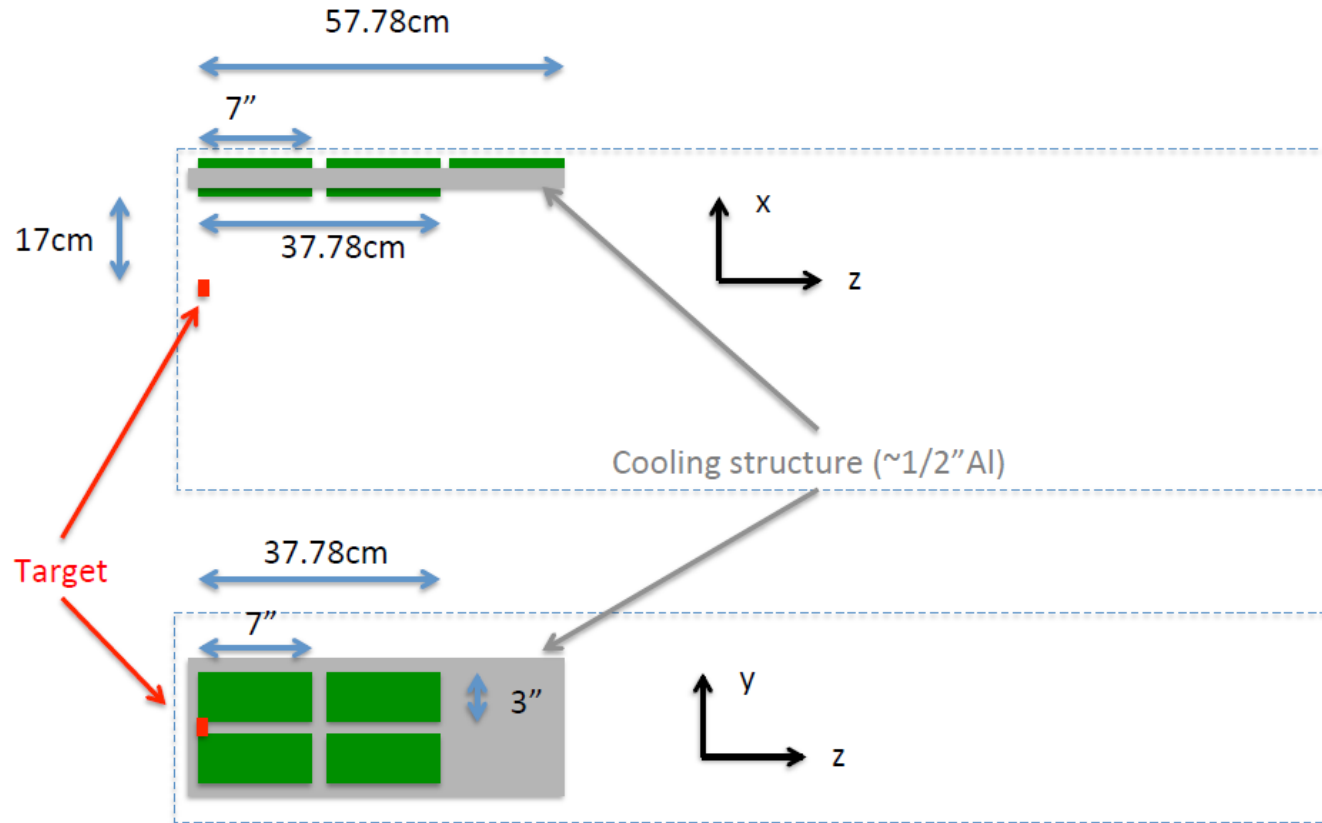


X-ray dose at FPGA

FE board positions



Energy deposition map

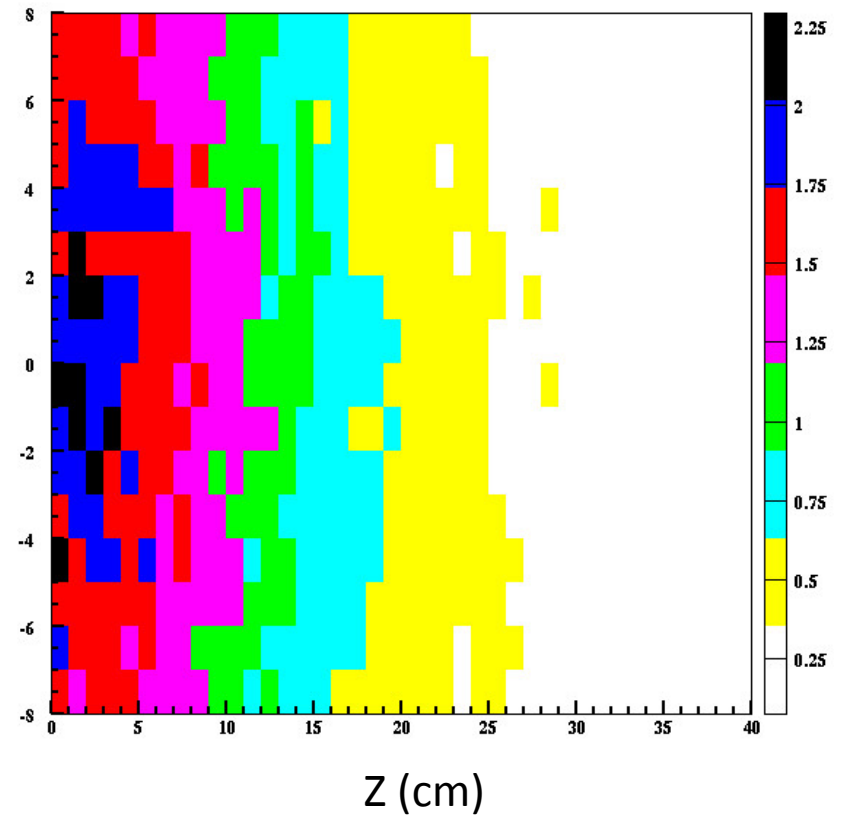
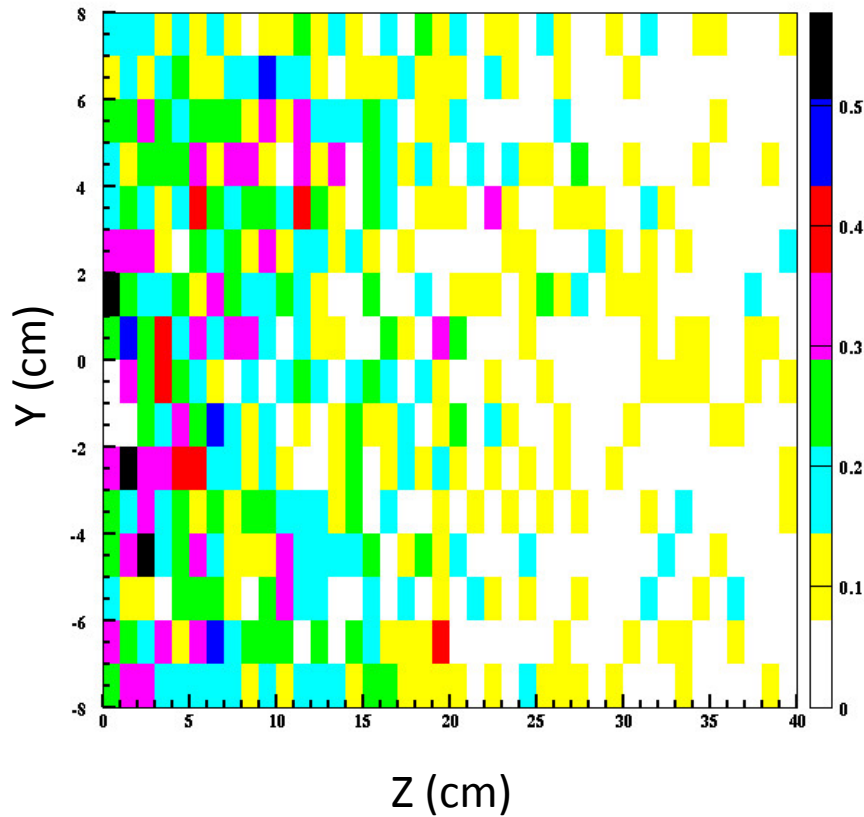
10^6 γ 's are uniformly distributed over 4π from the target.

K-shell 70 keV

MeV/cm²/10⁶ γ 's

L-shell 10 keV

MeV/cm²/10⁶ γ 's



Dose in FPGA

	Flux/sec at target	Energy deposition from 10^6 X-rays	Dose/hour	Dose/month (100% duty cycle)
K-shell	5.3×10^9 in 4π	0.5 MeV/ $1\text{cm} \times 1\text{cm} \times 700\mu\text{m}$	0.9 rad	648 rad
L-shell	8.3×10^9 in 4π	2.25 MeV/ $1\text{cm} \times 1\text{cm} \times 100\mu\text{m}$	45 rad	32krad
M-shell	2.8×10^9 in 2π	1.1 MeV/ $1\text{cm} \times 1\text{cm} \times 2\mu\text{m}$	800 rad	576krad

Require dose <10k/year:

⇒ K-shell is ok

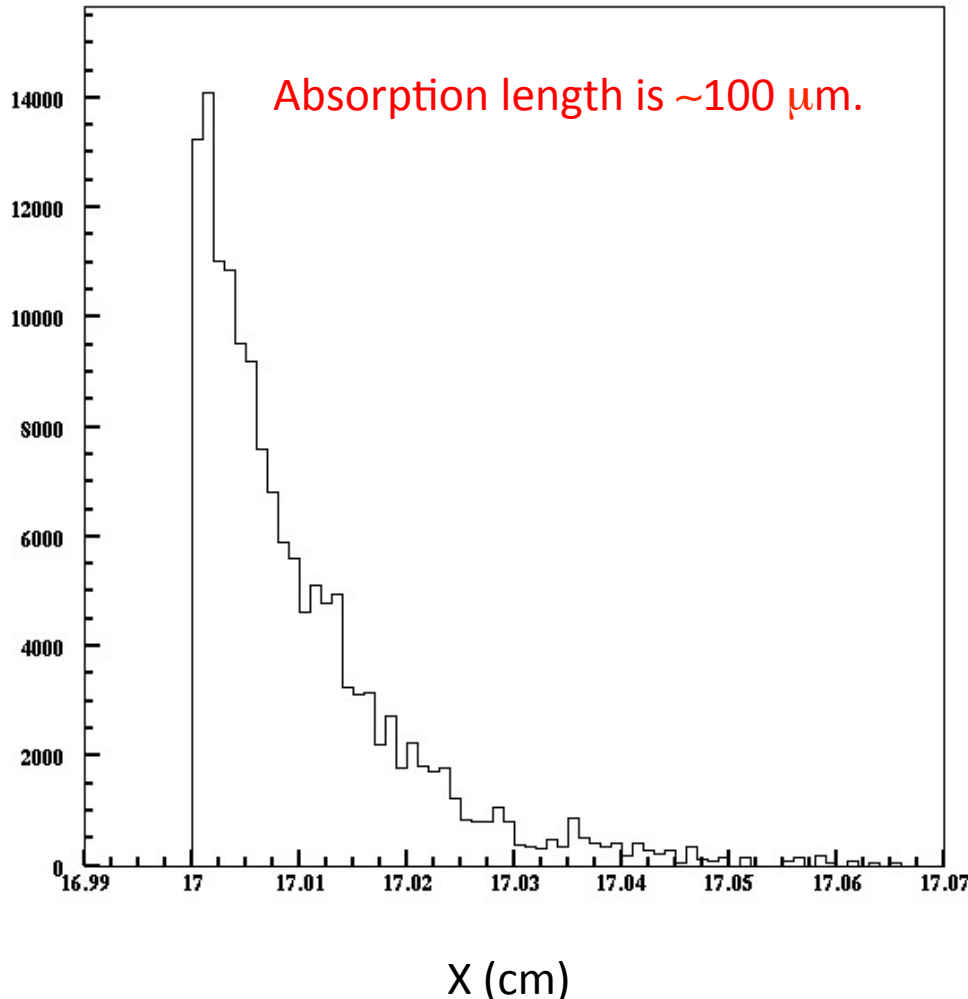
⇒ L-shell and M-shell need to be thought about.

⇒ Shielded from any Cu layer in board

⇒ Components on surface?

Energy deposition in depth

L-shell 10 keV



Silicon:

70 keV distributes energy ~uniformly in the FE board Si (and Al).

12keV will deposit 95% of the dose in first 300um of Si.

The 2keV is stopped by a few microns of Si ($\mu=1.54\mu\text{m}$, 99.5% in 7.7um)

Any copper layer in board will shield:

2keV (0.52um): 99.5% in 2um

10keV (5.2um): 99.5% in 25.8um

70keV (947um): 99.5% in 4.7mm

Example of shielding with a heavier element (tungsten):

2keV (0.13um): 99.5% in 0.66um

10keV (5.3um): 99.5% in 26.8um

70keV (46.3um): 99.5% in 46.3um